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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:
Choi, et al.

Serial No. 09/698,347

Filed: October 27, 2000

For: HIGH-PRECISION ORIENTATION
ALIGNMENT AND GAP CONTROL
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§ Atty. Dkt. 5119-08601

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I hereby certify that this correspondence is being deposited with the U.S. Postal Service with sufficient postage as First Class Mail, postage prepaid, in an envelope addressed to: Commissioner for Patents, Washington, D.C. 20231, on the date below:

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INFORMATION DISCLOSURE STATEMENT

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Commissioner for Patents
Washington, D.C. 20231

Sir:

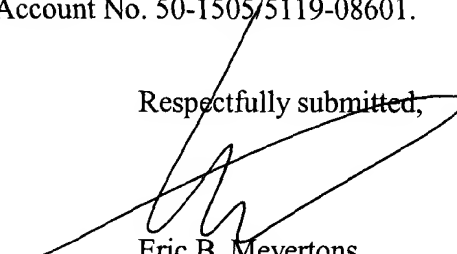
It is respectfully requested that this Information Disclosure Statement be entered and the documents listed on attached Form PTO-1449 (references A1-A118) be considered by the Examiner and made of record. A copy of each listed document is enclosed for the convenience of the Examiner.

Applicant also requests that the Examiner consider the following U.S. Patent applications with amendments, as noted: 09/908,455 (with amendment); 09/907,512 (with amendment); 09/920,341 (with amendment); 09/934,248 (with amendment); 09/976,681; and 09/908,765. Copies of these applications and amendments are enclosed for the convenience of the Examiner.

Choi, et al.
09/698,317

Should any fees be required, the Commissioner is authorized to charge said fees to Conley, Rose & Tayon, P.C. Deposit Account No. 50-1505/5119-08601.

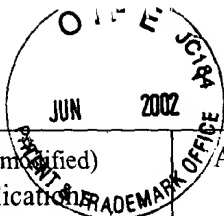
Respectfully submitted,



Eric B. Meyertons
Reg. No. 34,876
Attorney for Applicant(s)

CONLEY, ROSE & TAYON, P.C.
P.O. BOX 398
AUSTIN, TEXAS 78767-0398
(512) 476-1400

Date: 6/11/02

**Form PTO-1449** (modified)

List of Patents and Publications

For Applicant's Information

Disclosure Statement

(Use several sheets if necessary)

ATTY. DKT. NO. 5119-08601

APPLICANT: Choi et al.

FILING DATE: October 27, 2000

SERIAL NO. 09/698,317

GROUP: 2859

U.S. PATENT DOCUMENTS

EXAM. INITIALS	REF. DES.	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
	A1	3,807,027	4/1974	Heisler			
	A2	3,807,029	4/1974	Troeger			
	A3	3,811,665	5/1974	Seelig			
	A4	4,062,600	12/1977	Wyse			
	A5	4,098,001	7/1978	Watson			
	A6	4,155,169	5/1979	Drake et al.			
	A7	4,202,107	5/1980	Watson			
	A8	4,267,212	5/1981	Sakawaki			
	A9	4,337,579	7/1982	De Fazio			
	A10	4,355,469	10/1982	Nevens et al.			
	A11	4,414,750	11/1983	De Fazio			
	A12	4,451,507	5/1984	Beltz et al.			
	A13	4,610,442	9/1986	Oku et al.			
	A14	4,694,703	11/1987	Routson			
	A15	4,731,155	3/1988	Napoli et al.			
	A16	4,763,886	8/1988	Takei			
	A17	4,929,083	5/1990	Brunner			
	A18	4,959,252	11/1990	Bonnebat et al.			
	A19	5,072,126	12/1991	Progler			
	A20	5,110,514	5/1992	Soane			
	A21	5,126,006	6/1992	Cronin et al.			
	A22	5,204,739	4/1993	Domenicali			
	A23	5,240,550	8/1993	Boehnke et al.			
	A24	5,348,616	9/1994	Hartman et al.			
	A25	5,392,123	2/1995	Marcus et al.			
	A26	5,425,964	6/1995	Southwell et al.			
	A27	5,452,090	9/1995	Progler et al.			

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Form PTO-1449 (modified) List of Patents and Publications For Applicant's Information Disclosure Statement (Use several sheets if necessary)			ATTY. DKT. NO. 5119-08601 APPLICANT: Choi et al. FILING DATE: October 27, 2000		SERIAL NO. 09/698,317 GROUP: 2859		
PATENT DOCUMENTS							
EXAM. INITIALS	REF. DES.	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
	A28	5,480,047	1/1996	Tanigawa et al.			
	A29	5,512,131	4/1996	Kumar et al.			
	A30	5,515,167	5/1996	Ledger et al.			
	A31	5,545,367	10/1996	Bae et al.			
	A32	5,566,584	10/1996	Briganti et al.			
	A33	5,633,505	5/1997	Chung et al.			
	A34	5,724,145	3/1998	Kondo et al.			
	A35	5,753,014	5/1998	Van Rijn			
	A36	5,760,500	6/1998	Kondo et al.			
	A37	5,772,905	6/1998	Chou			
	A38	5,776,748	7/1998	Singhvi et al.			
	A39	5,779,799	7/1998	Davis			
	A40	5,802,914	9/1998	Fassler et al.			
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	A42	5,877,861	3/1999	Ausschnitt et al.			
	A43	5,888,650	3/1999	Calhoun et al.			
	A44	5,900,160	5/1999	Whitesides et al.			
	A45	5,912,049	6/1999	Shirley			
	A46	5,942,871	8/1999	Lee			
	A47	5,948,470	9/1999	Harrison et al.			
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	A51	6,046,056	4/2000	Parce et al.			
	A52	6,051,345	4/2000	Huang			
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	A54	6,091,485	7/2000	Li et al.			
	A55	6,128,085	10/2000	Buermann et al.			

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Form PTO-1449 (modified)

List of Patents and Publications

For Applicant's Information

Disclosure Statement

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ATTY. DKT. NO. 5119-08601

SERIAL NO. 09/698,317

APPLICANT: Choi et al.

GROUP: 2859

FILING DATE: October 27, 2000

U.S. PATENT DOCUMENTS

EXAM. INITIALS	REF. DES.	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
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	A57	6,168,845	1/2001	Fontana, Jr. et al.			
	A58	6,180,239	1/2001	Whitesides et al.			
	A59	6,204,922	3/2001	Chalmers			
	A60	6,334,960	1/2002	Wilson et al.			

FOREIGN PATENT DOCUMENTS

EXAM. INITIALS	REF. DES.	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS	TRANSLATION YES/NO
	A61	00/54107	9/2000	WO			
	A62	01/33232	5/2001	WO			
	A63	01/33300	5/2001	WO			
	A64	244884	3/1987	EP			
	A65	733455	9/1996	EP			NO
	A66	2800476	7/1978	DE			NO
	A67	19648844	11/1999	DE			NO
	A68	1-196749	8/1989	JP			NO

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A70	Paros, J.M.; Weisbord, L.; "How to Design Flexure Hinges", Machine Design, 1965, 151-156.		
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A72	Hogan, Neville; "Impedance Control: An Approach to Manipulation", Journal of Dynamic Systems, Measurement and Control, 1985, 107, 1-7.		
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A78	Peng, Zhi-Xin; Adachi, N.; "Compliant Motion Control of Kinematically Redundant Manipulators", IEEE Transactions on Robotics and Automation, 1993, 9, 831-837.		
A79	Rong, Y.; Zhu, Y.; Luo, Z.; Liu, X.; "Design and Analysis of Flexure-Hinge Mechanism Used in Micro-Positioning Stages", ASME, 1994, 2, 979-985.		
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Information Disclosure Statement--PTO 1449 (modified)

Form PTO-1449 (modified) List of Patents and Publications For Applicant's Information Disclosure Statement (Use several sheets if necessary)		ATTY. DKT. NO. 5119-08601 APPLICANT: Choi et al. FILING DATE: October 27, 2000	SERIAL NO. 09/698,317 GROUP: 2859
A87	Rong, L.; Guanghui; "Dynamics of Parallel Mechanism with Direct Compliance Control", IEEE, 1997, 1753-1758.		
A88	Mittal, Samir; Menq, Chia-Hsiang; "Precision Motion Control of Magnetic Suspension Actuator Using a Robust Nonlinear Compensation Scheme", IEEE/ASME Transactions on Mechatronics, 1997, 2, 268-280.		
A89	Physik Instruments, Product Catalog for Micropositioning, 1997.		
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A91	Lee, Chang-Woo; Kim, Seung-Woo; "Ultraprecision Stage for Alignment of Wafers in Advanced Microlithography", Precision Engineering, 1997, 21, 113-122.		
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A99	Xia, Y.; Whitesides, George; "Soft Lithography", Annu. Rev. Mater. Sci., 1998, 28, 153-184.		
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A101	Lee, Dong Sung et al.; "Ultra Precision Positioning System for Servo Motor-Piezo Actuator Using Dual Servo Loop and Digital Filter Implementation", ASPE, 1998, 18, 287-290.		
A102	Wu, Wei et al.; "Large Area High Density Quantized Magnetic Disks Fabricated Using Nanoimprint Lithography", 1998, Journal of Vacuum Science and Technology, 1998, 16, 3825-3829.		
A103	Ohya, Y. et al.; "Development of 3-DOF Finger Module for Micro Manipulation", Proc. of IEEE, Intl. Conf. on Intelligent Robots and Systems, 1999, 894-899.		
A104	Tanikawa, T. et al.; "Development of Small-Sized 3 DOF Finger Module in Micro Hand for Micro Manipulation", Proc. of IEEE, Intl. Conf. on Intelligent Robots and Systems, 1999, 876-881.		
A105	Colburn, M. et al.; "Step and Flash Imprint Lithography: New Approach to High-Resolution Patterning", Proc. of SPIE, 1999, 3676, 379-389.		

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